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PATENT
Attorney Docket No. 046124-5055

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Takuya HOMME, et al

Application No.: 09/737,818

Filed: December 18, 2000

For: ORGANIC FILM VAPOR DEPOSITION
METHOD AND A SCINTILLATOR PANEL

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Art Unit: 2878

Examiner: Timothy J. Moran

Notice of Allowance Mailed:
September 24, 2002

SEARCHED
INDEXED
ADDED

Commissioner for Patents
BOX ISSUE FEE
Washington, DC 20231

Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(d)

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(d), Applicants bring to the attention of the Examiner the documents listed on the attached PTO Form 1449. This Information Disclosure Statement (IDS) is being filed after the events recited in § 1.97(c) but before the payment of the issue fee for the above-identified application. Under the provisions of 37 C.F.R. § 1.97(d), a fee of \$180.00, as specified by § 1.17(p) is due for filing this IDS. The Commissioner is hereby authorized to charge this \$180.00 fee to Deposit Account No. 50-0310.

Each item of information contained in this IDS was first cited in a counterpart Japanese application in a communication issued by the Japanese Patent Office in August 2002. Applicants submit that each item of information contained in this IDS was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior

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to the filing of this IDS. A copy of each communication from the Japanese Patent Office is enclosed for the Examiner's consideration.

The following documents are listed on the accompanying PTO Form 1449 and are in a language other than English:

- 1. JP 63-216000.
- 2. JP 61-124574.
- 3. JP 63-215987.

As for relevance, a full or partial English translation having related text and/or an English language abstract is provided for each of the listed documents. Applicants also point out the following information.

The communication issued by the Japanese Patent Office was a Notice of Reason for Refusal citing the three documents listed on the enclosed Form PTO 1449. Applicants provide the following comments on one of the cited references, JP 61-124574, as follows.

Applicants submit that Japanese Patent Application Laid-open No. Sho 61-124574 discloses a method of performing chemical evaporation on a surface of a substrate in which during the chemical evaporation, the substrate is supported under a point contact status with tops of conical protrusions, and/or a meshed supporting member. However, Applicants submit that this reference does not disclose nor suggest that the substrate has formed thereon a radiation detection layer of columnar type material with deliquesces.

Copies of the listed documents are attached. Applicants respectfully request that the Examiner consider the listed documents and evidence that consideration by making appropriate notations on the attached PTO Form 1449.

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This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "Prior Art." If it should be determined that any of the listed documents do not constitute "Prior Art" under United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such documents.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any additional fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 50-0310.

Respectfully submitted,

MORGAN, LEWIS & BOCKIUS LLP

By:


John G. Smith
Registration No. 33,818

Dated: November 21, 2002

CUSTOMER NO. 009629
MORGAN, LEWIS & BOCKIUS LLP
1111 Pennsylvania Avenue, N.W.
Washington, D.C. 20004
Tel: 202-739-3000

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